

# Study and realization of a piezoelectric actuator/sensor by the laser manufacturing process

Hanane Taktak<sup>1</sup>, Patrick Rougeot<sup>1</sup>, Micky Rakotondrabe<sup>1</sup>, Joel Agnus<sup>1</sup>, Mounir Hammouche<sup>1</sup>, Joel Bafumba Liseli<sup>1</sup>

<sup>1</sup>Institute FEMTO-ST, (UMR 6174) CNRS, University of Bourgogne Franche-Comté, ENSMM, Besançon, France

## Objectives

Implementation of the laser manufacturing method.  
Realization of the piezoelectric actuator with collocated sensor modeled in [1].

## Materials

- Lead Zirconate Titanate (PZT)
- Polyvinylidene difluoride (PVDF)
  - Insulating glue

## Equipment

### Laser etching machine

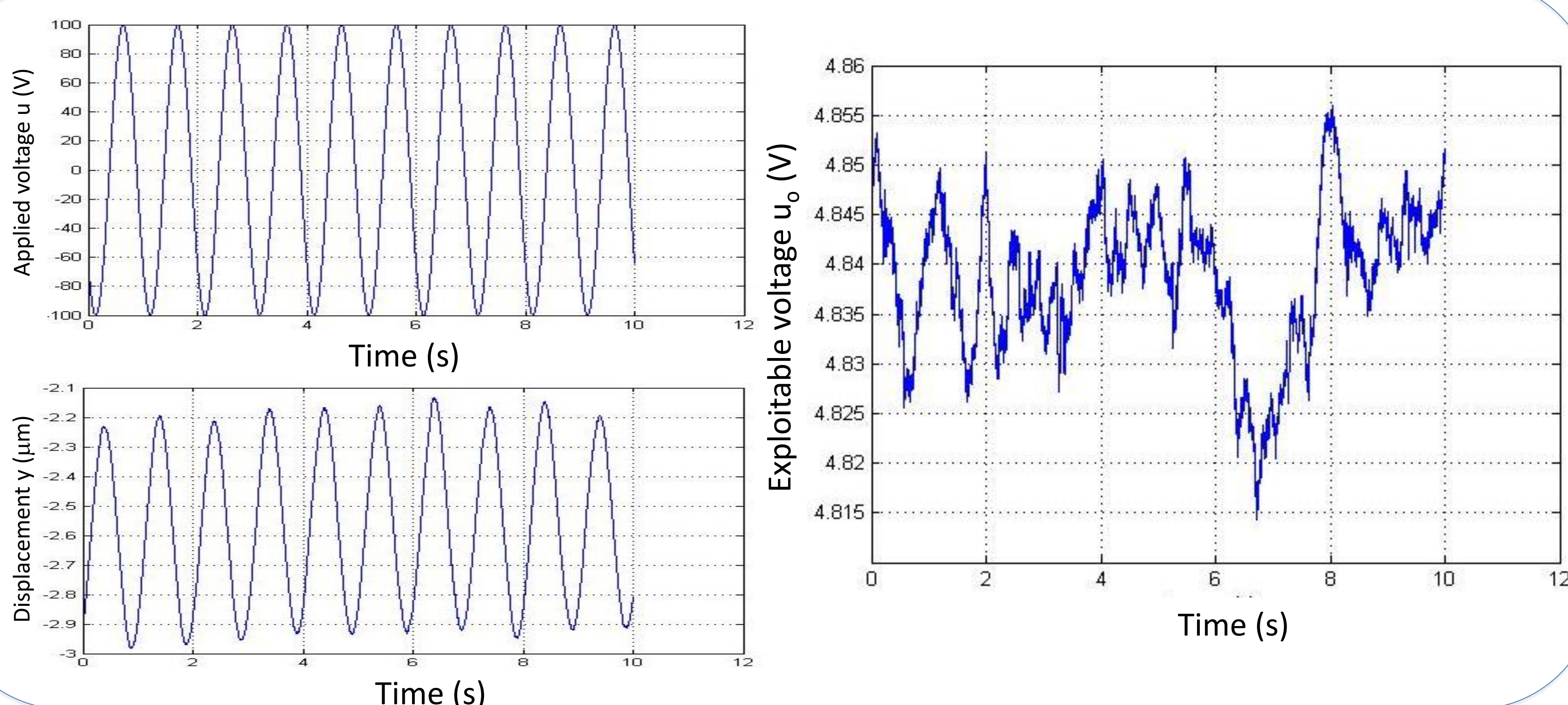


Fig. 1 Laser etching machine. 'Nison Lasertec'

## Advantages

- Fast, accurate, unalterable, durable, flexible.
- Work possible on many materials, and on all surfaces.
- Negligible influence on the piezoelectric constant  $d_{33}$ .

## Results



## Requirements

- Outer layers used for actuation (PZT)
- Middle layer used for detection (PVDF)
- Insulating adhesive used to avoid interference between the different electrodes.

## Principle

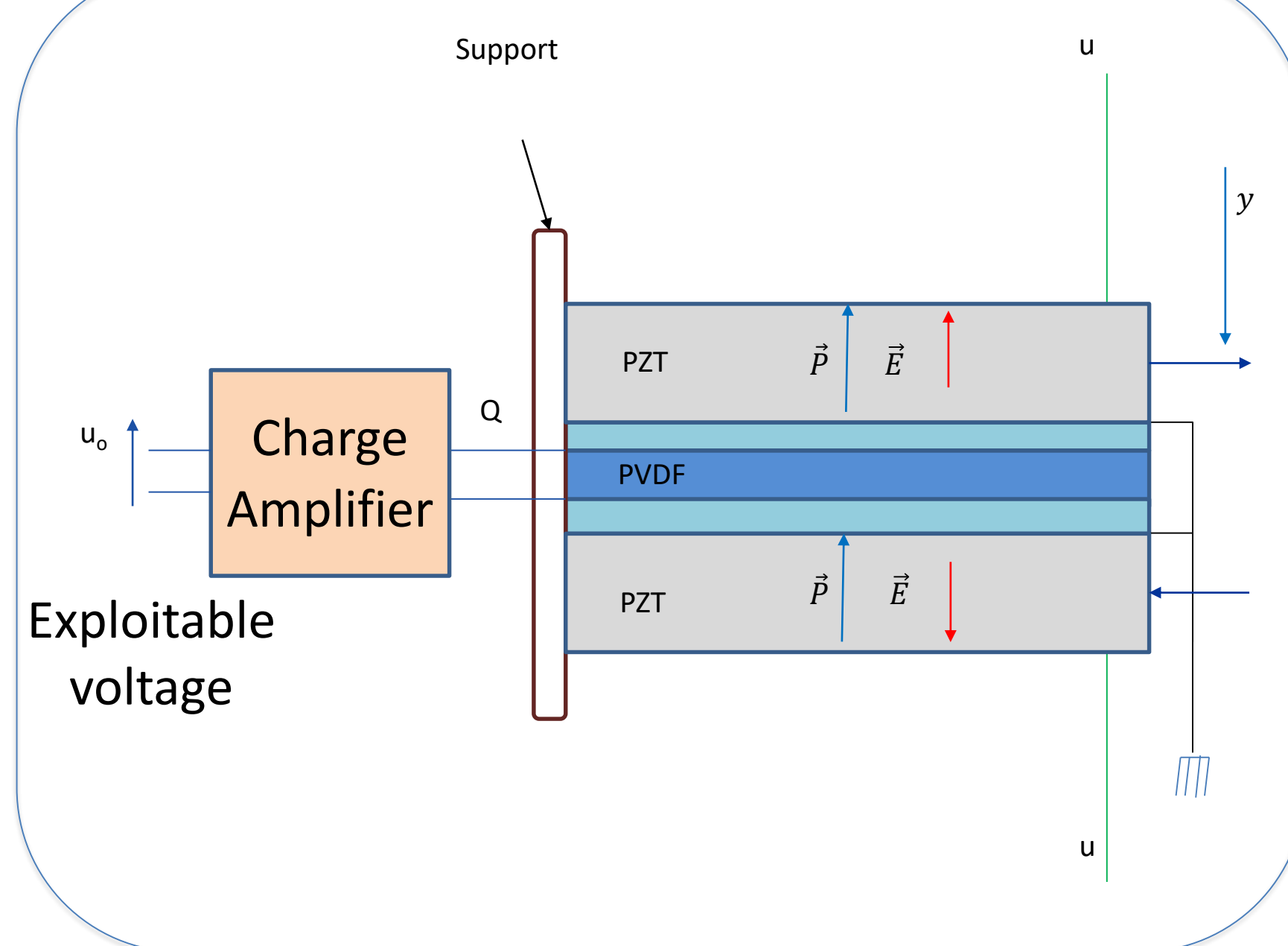


Fig. 3 Operating principle of the piezoelectric actuator with collocated sensor.



Fig. 5 Support designed with AutoCAD and 3D printed.

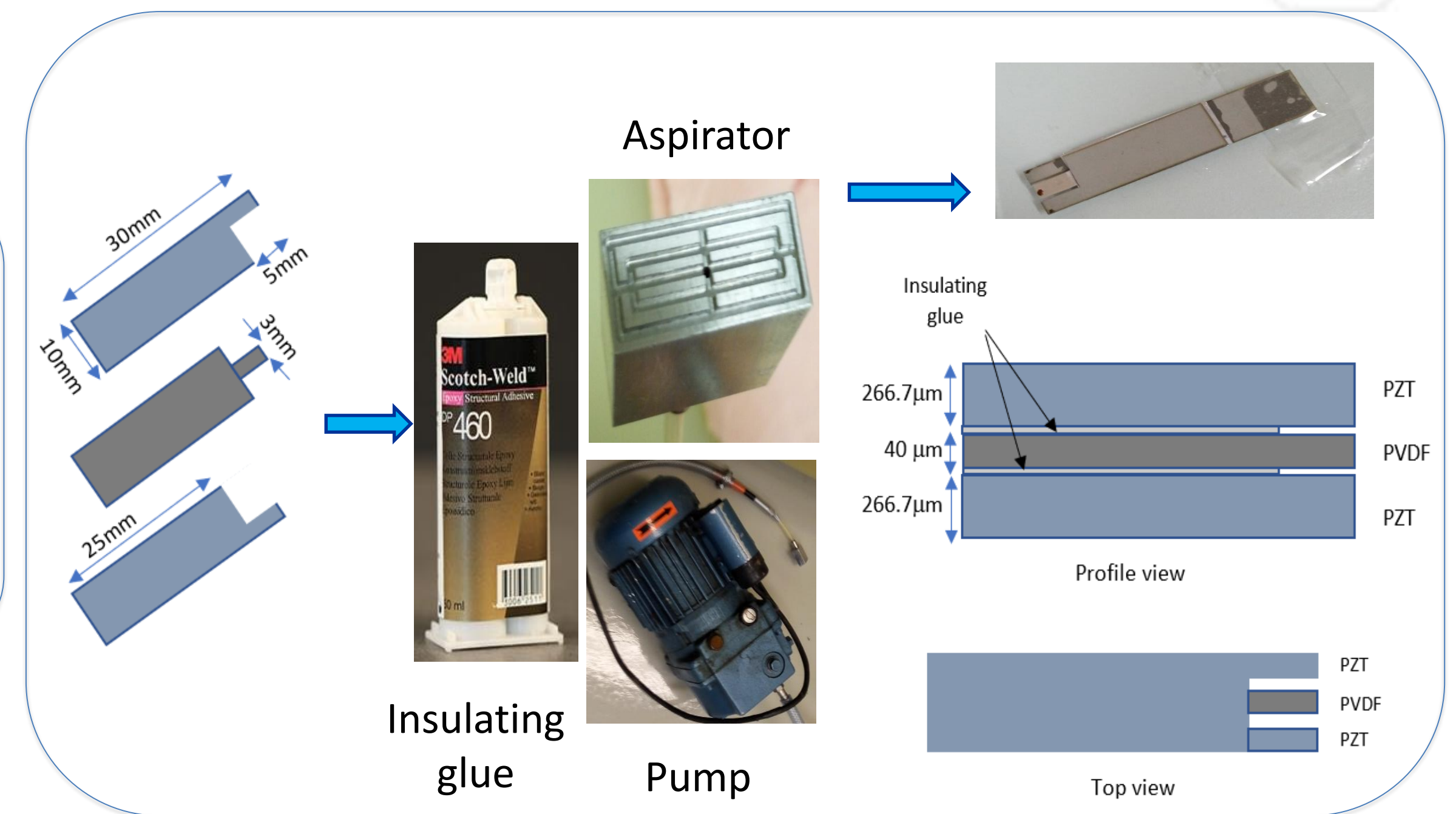


Fig. 2 Structure and dimensions of the piezoelectric actuator with collocated sensor.

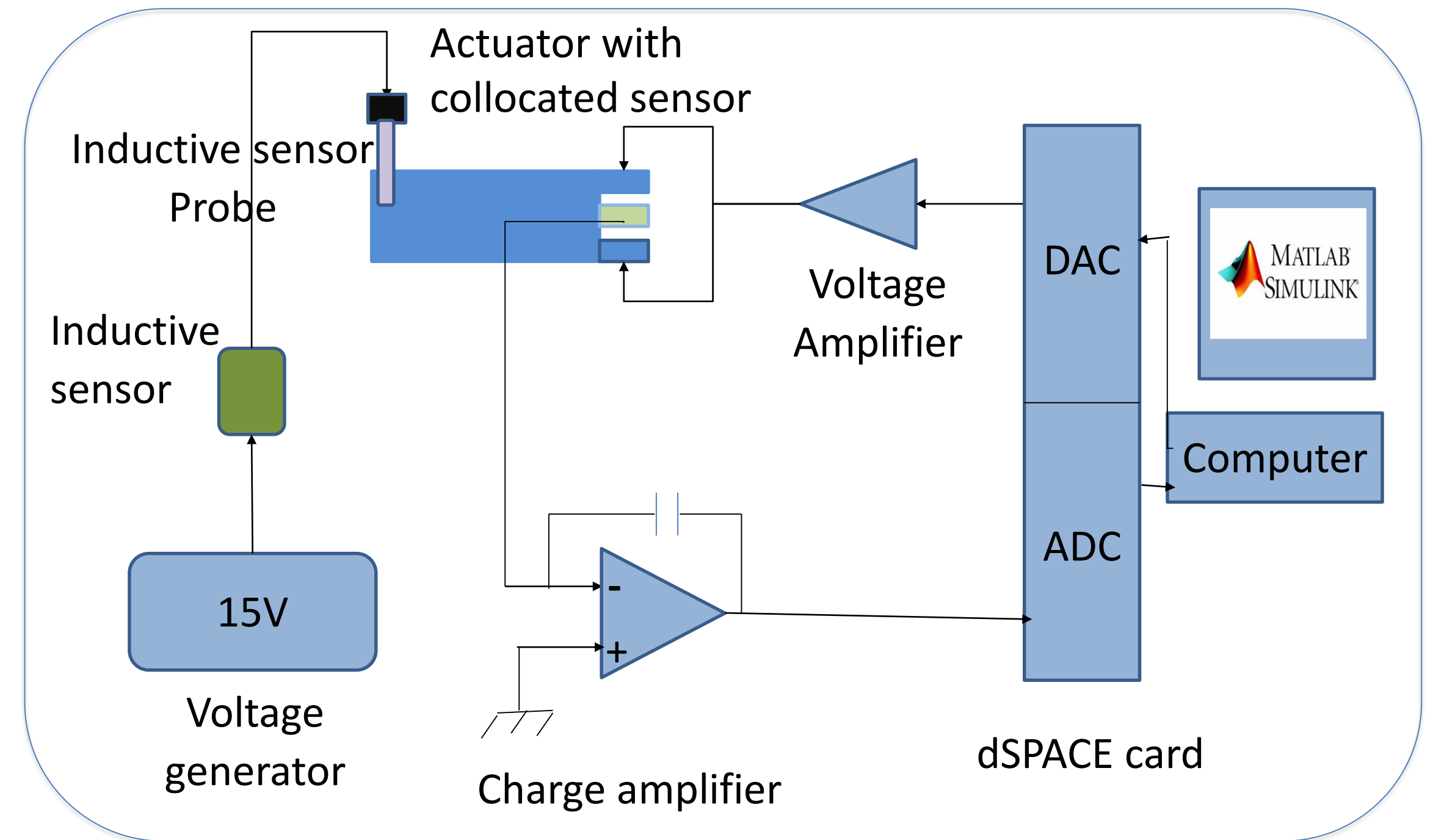


Fig. 4 Diagram of the electrical circuit.

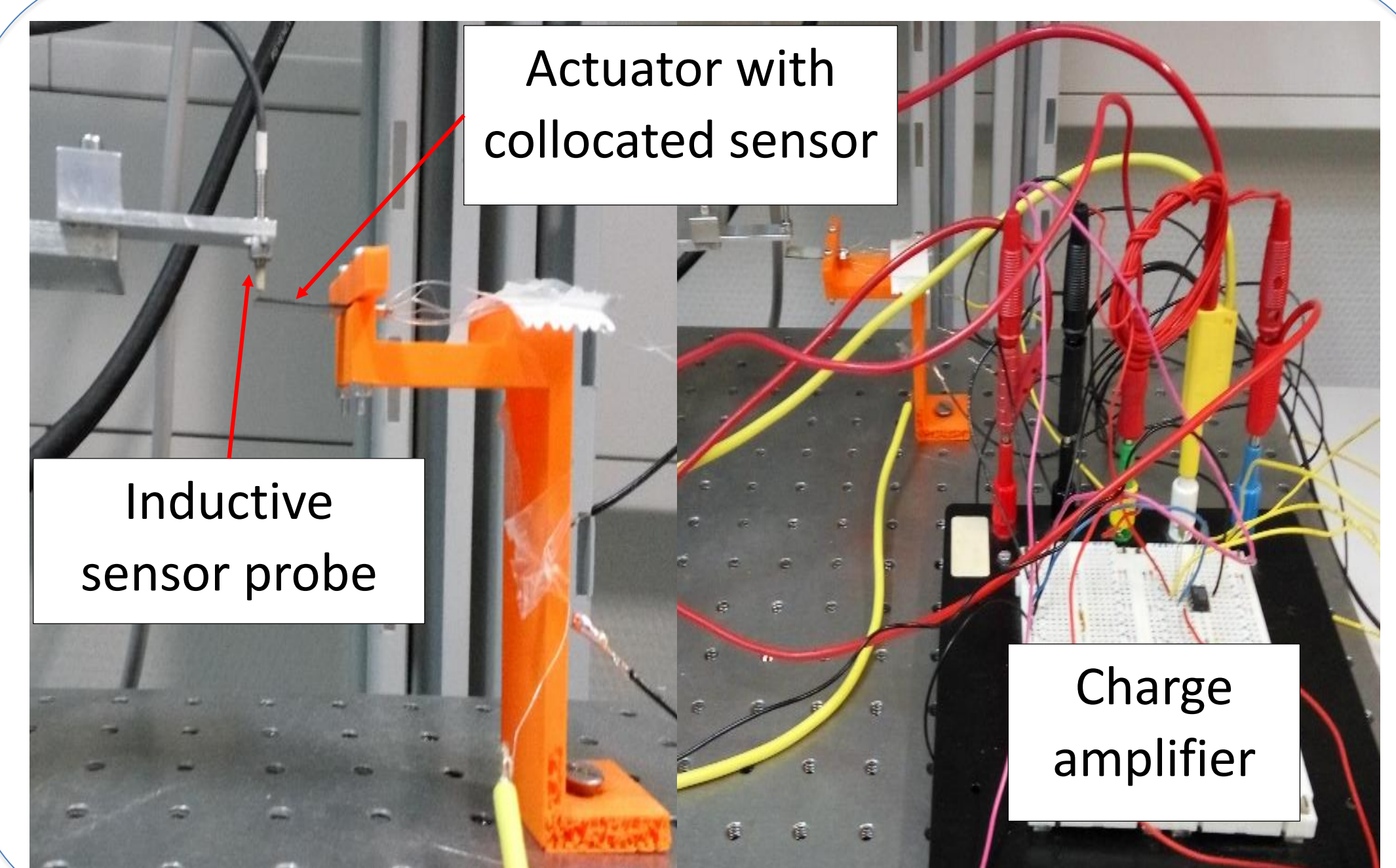


Fig. 6 Electrical circuit.

## Conclusion

- Several processes have been implemented during this project such as laser etching, bonding of layers and silver welding of electrical wires.
- Our piezoelectric actuator with collocated sensor works well in both operating modes: actuation and detection.
- The load generated by the integrated sensor is converted into an exploitable voltage  $\approx 4.83$  V.

## Reference

[1] P. Rougeot, A. Mohand-Ousaid, D. Gendreau, M. Hammouche and M. Rakotondrabe "Design, modeling and simulation of a three-layers piezoelectric cantilevered actuator with collocated sensor", *Sensors for Next-Generation Robotics III*, 98590F.USA 2016.